



501.30598CC3

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MORIOKA, et al

Serial No.: 09/805,188

Filed: March 14, 2001

For: METHOD AND APPARATUS FOR ANALYZING THE STATE OF
GENERATION OF FOREIGN PARTICLES IN
SEMICONDUCTOR FABRICATION PROCESS

Group: 2877

Examiner: T. Nguyen

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5/10
G. Stanley

1-29-02

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

January 15, 2002

Sir:

The following amendments and remarks are respectfully
submitted in connection with the above-identified application
in response to the Office Action dated November 15, 2001.

IN THE SPECIFICATION:

Page 1, please amend the paragraph beginning at line 5 as
follows:

Cross-Reference to Related Applications

01
This application is a continuation application of U.S.
application Serial No. 08/535,577, filed September 28, 1995,
which is a continuation application of U.S. application Serial

01/18/2002 HGBREM1 00000029 09805188

02 FC:102
03 FC:103

420.00 OP
90.00 OP